Matter No.: 10559-882001 Page Applicant: Yan Borodovsky COMPOSITE OPTICAL LITHOGRAPHY METHOD FOR PATTERNING LINES OF UNEQUAL WIDTH

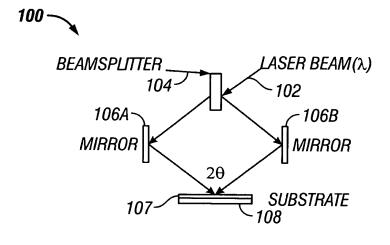


FIG. 1A

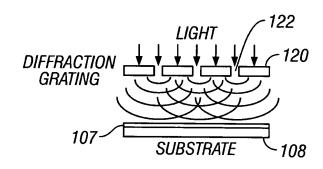


FIG. 1B

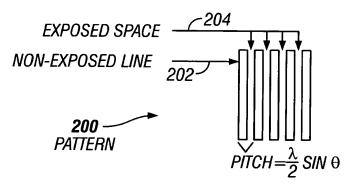
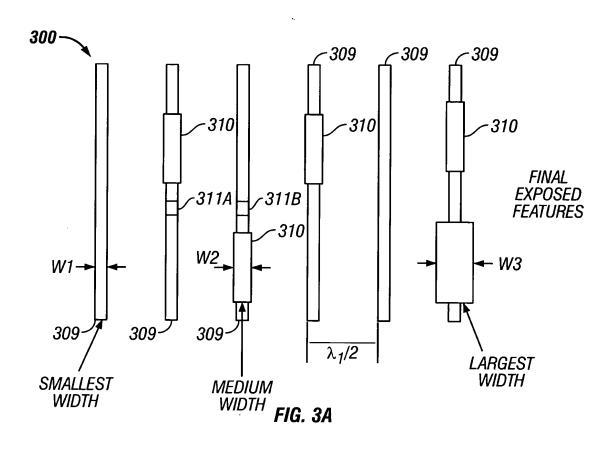


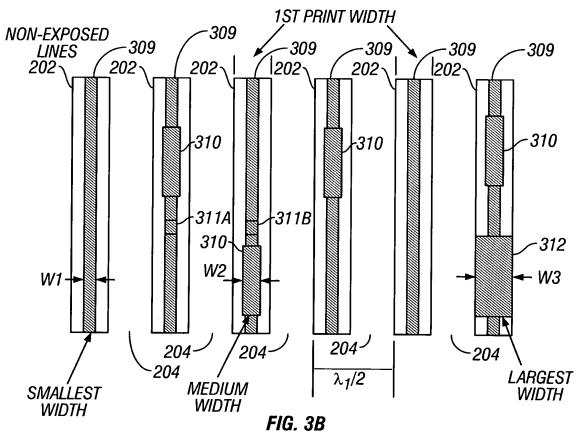
FIG. 2

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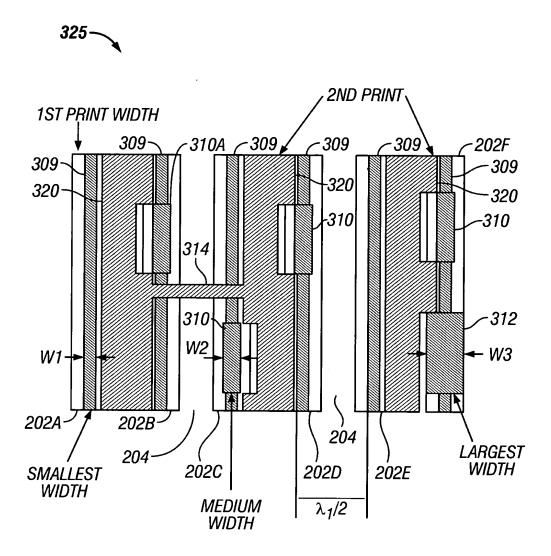


FIG. 3C

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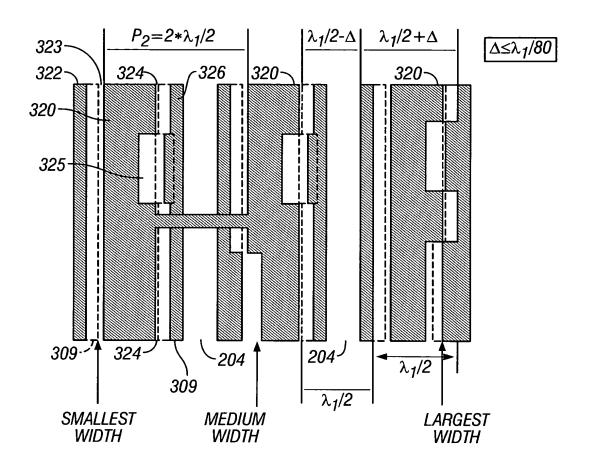
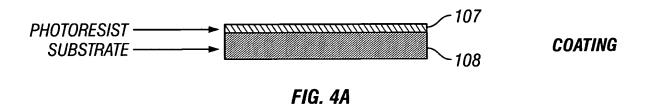
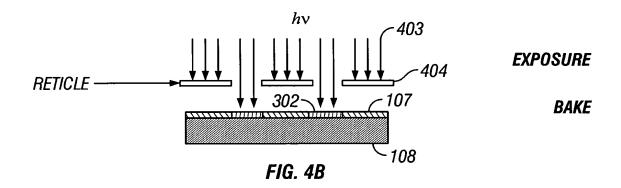


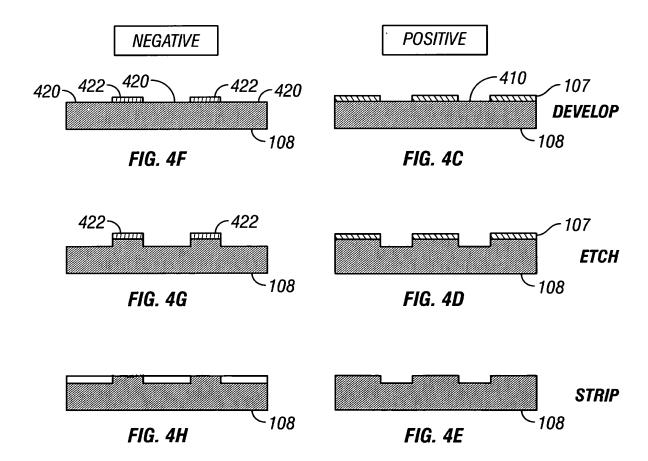
FIG. 3D

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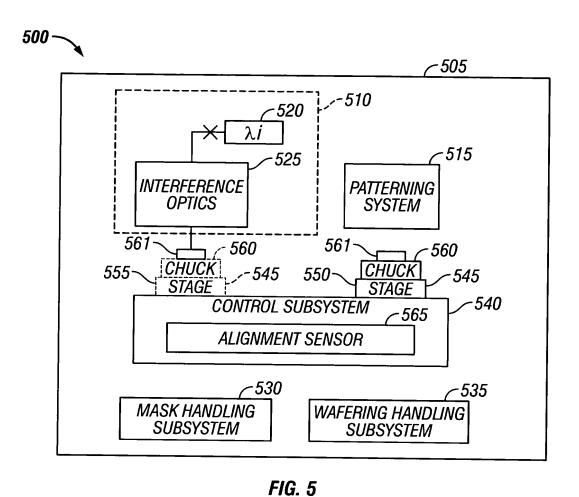




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COMPOSITE OPTICAL LITHOGRAPHY METHOD FOR



620

APERTURE/
CONDENSER

610

MASK STAGE
MASK
PROJECTION
OPTICS

FIG. 6

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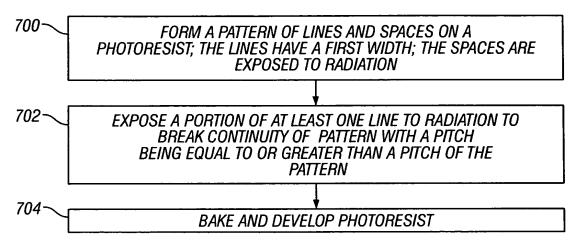


FIG. 7

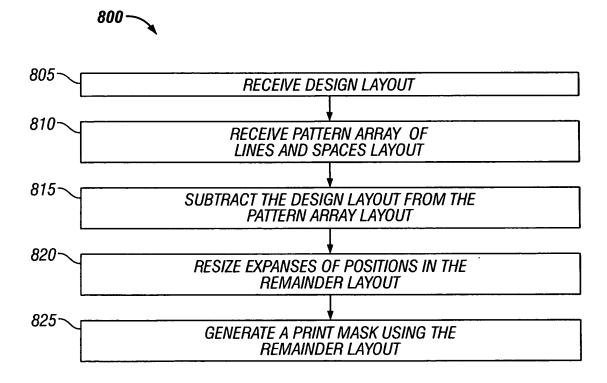
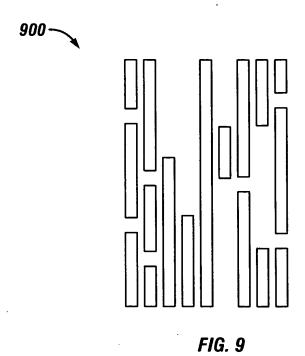


FIG. 8

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1000 1100 1005 1105 1105-1010 -1110 1005 -1105 1105 1005 D 1105-1005 1005 1005 1005 1105-1005 -1105 FIG. 10 FIG. 11